

10/06/01  
12/03/01

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10006100	FILING DATE 12/03/2001	CLASS 438	SUBCLASS 345.33	GAU 2812	EXAMINER ZERVIGON
<b>**APPLICANTS:</b> Shepherd Robert; Caughran James;					
<b>**CONTINUING DATA VERIFIED:</b> N/A 2/7 8/24/3					
<b>** FOREIGN APPLICATIONS VERIFIED:</b> N/A 2/7 8/24/3					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input checked="" type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO NOVEP015	
Verified and Acknowledged Examiners's initials					
TITLE : Method and apparatus for plasma optimization in wafer processing					

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436 (Rev. 12-94)

<b>NOTICE OF ALLOWANCE MAILED</b>		<b>CLAIMS ALLOWED</b>	
		Total Claims	Print Claim for O.G.
<b>ISSUE FEE</b>		<b>DRAWING</b>	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> <b>TERMINAL DISCLAIMER</b>		Application Examiner	
		<b>PREPARED FOR ISSUE</b>	
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